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**Förster**

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(54) **SYSTEMS AND METHODS FOR TREATING WORKPIECES**

(56) **References Cited**

(71) Applicant: **DÜRR ECOCLEAN GMBH**,  
Filderstadt (DE)

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(72) Inventor: **Michael Förster**, Eupen (BE)

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(73) Assignee: **Dürr Ecoclean GMBH**, Filderstadt  
(DK)

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*Primary Examiner* — Duy Deo

*Assistant Examiner* — Maki Angadi

(74) *Attorney, Agent, or Firm* — Hanley, Flight & Zimmerman, LLC

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(57) **ABSTRACT**

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Example systems and methods for treating workpieces are disclosed. In some examples, the system includes a treatment station positioned in a process chamber for treating the workpiece with fluid. The example system includes a handling device positioned in the process chamber. The example handling device includes a base positioned in the process chamber, a supporting arm coupled to the base and pivotable relative to the base about a first pivot axis, a pivoting arm coupled to the supporting arm and pivotable relative to the supporting arm about a second pivot axis, and a receptacle coupled to the pivoting arm and including a workpiece holder capable of picking up the workpiece from a workpiece feeder positioned outside of the process chamber. The example handling device is capable of moving the workpiece through an opening of the process chamber and into a treatment position at the treatment station.

**19 Claims, 11 Drawing Sheets**

